

CLAIM AMENDMENTS:

1. (currently amended) An optical resonator including an apparatus for locking a bending mechanism that bends a reflex type wavelength selection element constituting a part of the optical resonator according to curvature of wavefront of an incident laser beam, which comprises locking means for locking the bending mechanism at any [[an]] adjusted position so as to hold a curvature of the wavelength selection element constant against a mechanical shock applied to the optical resonator and making adjustment of the curvature of the wavelength selection element impossible when the bending mechanism is locked by the locking means, wherein the locking means and the bending mechanism are separate structures.

2. (currently amended) An optical resonator including an apparatus for locking a bending mechanism that bends a reflex type wavelength selection element constituting a part of an optical resonator according to curvature of wavefront of an incident laser beam, which comprises adjustment means for varying a position of a grating that modifies the curvature of wave front of an incident laser beam to [[an]] any adjusted position of the curvature of wavefront, and locking means for locking the adjustment means in [[an]] the adjusted position so as to hold a curvature of the wavelength selection element constant against a mechanical shock applied to the optical resonator and preventing adjustment of the curvature of the wavelength selection element by the adjustment means when locked by the locking means.

3. (currently amended) An ~~apparatus for locking a bending mechanism~~
optical resonator as set forth in claim 1, wherein the locking means includes a locking screw.

4. (currently amended) An ~~apparatus for locking a bending mechanism~~
optical resonator as set forth in claim 2, wherein the locking means includes a locking screw.

5. (new) An optical resonator as set forth in claim 1, wherein the adjusted position can be adjusted at a nanometer level of measurement.

6. (new) An optical resonator as set forth in claim 2, wherein the adjusted position can be adjusted at a nanometer level of measurement.